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13  
14  
15 **UNITED STATES DISTRICT COURT**  
16 **NORTHERN DISTRICT OF CALIFORNIA**

17 APPLIED MATERIALS, INC.,  
18 Plaintiff,  
19 vs.  
20 DR. URI COHEN,  
21 Defendant.

Lead Case No. 3:17-cv-04990-EMC  
Consolidated with  
Case No. 3:17-cv-06451-EMC  
Case No. 3:17-cv-05001-EMC

**PLAINTIFF DR. URI COHEN'S THIRD  
CONSOLIDATED AMENDED  
COMPLAINT AND ANSWER TO  
COMPLAINT FOR DECLARATORY  
JUDGMENT**

Date: June 7, 2018  
Time: 10:30am  
Dept.: Courtroom 5, 17th Floor  
Judge: Hon. Edward M. Chen

1 TSMC NORTH AMERICA; TAIWAN  
2 SEMICONDUCTOR MANUFACTURING  
COMPANY LIMITED,

3 Plaintiffs,

4 v.

5 URI COHEN,

6 Defendant.

7 DR. URI COHEN,

8 Plaintiff,

9 v.

10 TAIWAN SEMICONDUCTOR  
11 MANUFACTURING COMPANY LTD.,  
HUAWEI DEVICE USA INC., HUAWEI  
12 DEVICE (DONGGUAN) CO. LTD.,

13 Defendants.

14  
15 Dr. Uri Cohen brings this action against Taiwan Semiconductor Manufacturing Company,  
16 Ltd., TSMC North America Corp., Huawei Device USA, Inc., Huawei Device (Dongguan) Co.,  
17 Ltd., Huawei Device Co., Ltd., HiSilicon Technologies Co., Ltd. (collectively, “Huawei”), and  
18 Applied Materials, Inc., and alleges as follows:<sup>1</sup>

19  
20 **THE PARTIES**

21 1. Plaintiff Dr. Uri Cohen (“Plaintiff” or “Dr. Cohen”) is a United States citizen, with  
22 a residence of 4147 Dake Ave., Palo Alto, CA 94306.

23 2. Defendant Taiwan Semiconductor Manufacturing Company Ltd. is a Taiwanese  
24 corporation and is headquartered at No. 8, Li-Hsin Rd. VI, Hsinchu, Taiwan 300, R.O.C., and has  
25

26  
27 \_\_\_\_\_  
28 <sup>1</sup> Except where otherwise noted or apparent from context, any allegation against “Defendants,”  
“TSMC,” or “Huawei,” is an allegation directed to every defendant subsumed within that name.

1 as its wholly owned U.S. subsidiary Defendant TSMC North America Corp., headquartered at 2585  
2 Junction Avenue, San Jose, California 95134 (collectively, “TSMC”).

3 3. Defendant Huawei Device USA, Inc. (“Huawei USA”) is a Texas corporation with  
4 its principal place of business in Plano, Texas. Huawei USA distributes, markets, and sells mobile  
5 devices, including smartphones in the United States.

6 4. Defendant Huawei Device (Dongguan) Co., Ltd. (“Huawei Dongguan”) is a Chinese  
7 company with a principal place of business at Building A, Cloud Park, Huacheng Road, Bantian,  
8 Longgang District, Shenzhen 518054, China. Huawei Dongguan is involved in the design,  
9 manufacture, and sale of mobile devices.

10 5. Defendant Huawei Device Co., Ltd. (“Huawei Device”) is a Chinese company with  
11 a principal place of business at 8 Shitou Road, North Area, Shenzhen, 518129, China. Huawei  
12 Device is involved in the design, manufacture, and sale of mobile devices. Huawei Device’s  
13 subsidiaries in the United States include Huawei Device USA, Inc.

14 6. Defendant HiSilicon Technologies Co., Ltd. (“HiSilicon”) is a Chinese company  
15 with its principal place of business in Bantian, Longgang District, Shenzhen, People’s Republic of  
16 China. On information and belief, HiSilicon is a subsidiary of Huawei China, and has a design  
17 division in Silicon Valley, U.S.A.

18 7. Defendant Applied Materials, Inc., (“AMAT”) is a Delaware corporation with a  
19 principal place of business located at 3050 Bowers Avenue, Santa Clara, California, 95052.

20  
21  
22  
23 **JURISDICTION AND VENUE**

24 8. This action arises under the patent laws of the United States, Title 35 United States  
25 Code, particularly §§ 271 and 281. This Court has jurisdiction over these claims for patent  
26 infringement under 28 U.S.C. §§ 1331 and 1338(a).



1           17.     On April 3, 2007, U.S. Patent No. 7,199,052 entitled “Seed Layers for Metallic  
2 Interconnects” (“the ’052 patent,”) was duly and legally issued. Exhibit D to Dkt. No. 1 is a true  
3 and correct copy of the ’052 patent.

4           18.     Pursuant to 35 U.S.C. § 282, the ’052 patent is presumed valid.

5           19.     Dr. Cohen is the owner of the entire right, title, and interest in the ’052 patent,  
6 including the right to sue and collect damages for past, present, and future infringement (to the  
7 extent those remedies are available to him).

8           20.     On October 16, 2007, U.S. Patent No. 7,282,445 entitled “Multiple Seed Layers for  
9 Interconnects” (“the ’445 patent,”) was duly and legally issued. Exhibit E to Dkt. No. 1 is a true  
10 and correct copy of the ’445 patent.

11           21.     Pursuant to 35 U.S.C. § 282, the ’445 patent is presumed valid.

12           22.     Dr. Cohen is the owner of the entire right, title, and interest in the ’445 patent,  
13 including the right to sue and collect damages for past, present, and future infringement (to the  
14 extent those remedies are available to him).

15           23.     The ’668 patent, ’226 patent, ’052 patent, and ’445 patent will hereinafter be referred  
16 to collectively as the “patents-in-suit.”

17           24.     To the extent required, Dr. Cohen has complied with the marking provisions of 35  
18 U.S.C. § 287 and is thus entitled to past damages.

19                           **DR. COHEN’S PRIOR COMMUNICATIONS WITH TSMC**

20           25.     Dr. Cohen was first introduced to TSMC in October 2000. After getting in touch  
21 with Mr. Henry Lo of TSMC in Taiwan, Dr. Cohen was invited by TSMC to present his Seed  
22 Layers technologies to TSMC in Hsinchu, Taiwan. Dr. Cohen provided TSMC a presentation of  
23 his technologies on April 10, 2001. Among other things, Dr. Cohen explained to TSMC how it  
24 could use a chemical vapor deposition (“CVD”) seed layer followed by a physical vapor deposition  
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26  
27  
28

1 (“PVD”) seed layer over a barrier layer to enable reliable void-free electrofill of openings narrower  
2 than 0.10 micron for TSMC’s current and future generations of interconnects.

3 26. After the meeting in Hsinchu in April 2001, Dr. Cohen followed up a number of  
4 times with TSMC in subsequent months. Ultimately, TSMC declined at that time to collaborate  
5 with Dr. Cohen, or take a license to Dr. Cohen’s patent-pending technologies.

6 27. In 2003, Dr. Cohen reached out again to TSMC, getting in touch with Dr. Rick Tsai,  
7 the president of TSMC at that time. Dr. Cohen had several communications with Dr. Tsai in which  
8 Dr. Cohen suggested to TSMC that it take a license to what Dr. Cohen referred to as his “Seed  
9 Layer Portfolio,” and indicated that several patents had issued, including U.S. Patent No. 6,518,668  
10 and a Taiwanese counterpart. Dr. Cohen explained to TSMC, among other things and as he had  
11 done before, that as geometries of semiconductor chips become smaller, Dr. Cohen’s patented  
12 technology would become more relevant to TSMC’s chip designs and methods of  
13 fabrication. Once again, TSMC declined to take a license to Dr. Cohen’s patents.

14 28. On July 23, 2004, Dr. Cohen (through his counsel) sent a letter to Dr. Richard  
15 Thurston, TSMC’s then-Vice President and General Counsel, drawing TSMC’s attention once  
16 again to the ’668 patent, among others, and providing TSMC a copy of the ’668 patent. Included  
17 with that letter, Dr. Cohen provided TSMC a general description of the patented technology and  
18 patents pending in Dr. Cohen’s Seed Layer Portfolio.

19 29. Dr. Cohen also provided TSMC with claim charts explaining the manner in which  
20 certain of Dr. Cohen’s claims would be infringed by specific forms of interconnects, including  
21 representative claim charts for the ’668 patent. Having received no reply from Dr. Thurston, on  
22 October 12, 2004 Dr. Cohen sent another letter to Dr. Thurston, in which he strongly recommended  
23 that TSMC consider taking a license to Dr. Cohen’s patents. He urged that even if TSMC did not  
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26  
27  
28

1 yet use Dr. Cohen's patented technology, it soon likely would as its technology nodes moved to  
2 smaller geometries.

3 30. Thereafter, from 2004 through 2007, Dr. Cohen's counsel communicated with  
4 TSMC on numerous occasions concerning Dr. Cohen's patented technology.

5 31. For example, on May 1, 2006, Dr. Cohen's counsel sent a letter to Steven Slater,  
6 Esq., TSMC's outside counsel with the law firm Slater & Matsil, LLP, drawing TSMC's attention  
7 to the '226 patent, among others, and providing TSMC a copy of the '226 patent and explaining  
8 how TSMC would infringe the '226 patent if it employed certain processing methods.  
9

10 32. That letter also identified to TSMC Dr. Cohen's U.S. Application No. 2007-  
11 0117379, which subsequently matured into the '052 patent.

12 33. TSMC denied again that it was infringing any of Dr. Cohen's patents, and in a letter  
13 dated October 6, 2006, explained:  
14

15 We would like to leave the door open to licensing Dr. Cohen's patents in the  
16 future, should TSMC elect to adopt multiple layer seed processes that are relevant  
17 to Dr. Cohen's patent claims, but TSMC is not using such technology at the  
18 present time and has no current plans to do so.

19 34. In a letter dated June 29, 2007, Dr. Cohen's counsel directed TSMC's attention to,  
20 among others, claims 10, 17, 18, 26, 33, 34, 53, and 58, of the '052 patent.

21 35. As further evidence that TSMC has been well aware of Dr. Cohen's patented  
22 technology, TSMC has referenced Dr. Cohen's '668 patent in no less than 15 of its own patents  
23 and patent applications, including U.S. Patent Nos. 6806192, 6943111, 7067409, 7215024,  
24 7265038, 7378744, 8277619, and U.S. Patent Applications Nos. 20040147104, 20040157431,  
25 20050029665, 20050110147, 20050250320, 20050263902, 20060216916, and 20070010080.

26 **DR. COHEN'S PRIOR COMMUNICATIONS WITH AMAT**

27 36. Dr. Cohen and his technology are well known to AMAT.  
28

1 37. Dr. Cohen and AMAT have had periodic discussions about Dr. Cohen's inventions  
2 since as early as November of 1999.

3 38. In February 2003, Dr. Cohen had communications with a representative of AMAT  
4 concerning the issuance of the '668 patent.

5 39. In September 2007, Dr. Cohen had further communications with AMAT about his  
6 patented technology, specifically identifying all four of the patents-in-suit, and other patents  
7 owned by Dr. Cohen.  
8

9 **BACKGROUND FACTS CONCERNING ACCUSED PRODUCTS**

10 40. All preceding paragraphs are incorporated by reference as if fully set forth herein.

11 41. An integrated circuit is a set of electronic circuits integrated on semiconductor  
12 material, which is most often silicon. These are often referred to as "semiconductor devices" or  
13 "semiconductor chips." These semiconductor chips are used in electronics, computers, and  
14 smartphones, among other devices.  
15

16 42. AMAT supplies chip manufacturers like TSMC with tools for manufacturing  
17 integrated circuits, including AMAT's Endura platform and Endura Volta CVD Cobalt system (the  
18 "AMAT Volta System").<sup>2</sup>

19 43. The AMAT Volta System was introduced by AMAT on May 13, 2014.<sup>3</sup>

20 44. On information and belief, AMAT provides the AMAT Volta System to TSMC and  
21 other chip manufacturers in the United States and abroad ("AMAT Customers").  
22

23 45. TSMC and other AMAT Customers fabricate integrated circuits, including those  
24 using TSMC's 20 and 16 nanometer node finFET process, according to the process described in  
25

26 \_\_\_\_\_  
27 <sup>2</sup> <http://www.appliedmaterials.com/products/endura-volta-cvd-cobalt>

28 <sup>3</sup> <http://www.appliedmaterials.com/company/news/press-releases/2014/05/applied-materials-introduces-the-biggest-materials-change-to-interconnect-technology-in-15-years>



1 AMAT's "Volta Animation," *see infra* note 15 ("the Accused Chips"). They then provide the  
2 Accused Chips to a number of electronics companies like Huawei and Apple.

3 46. For example, TSMC fabricates the HiSilicon Kirin 950 and 955 chips (16nm) for  
4 Huawei for use in at least the Huawei P9 and Huawei Honor 8 Smartphones (the "Huawei Chips").

5 47. TSMC also fabricates the Apple A8 (20nm), Apple A9 (16nm), and Apple A10  
6 (16nm) Applications Processors (and their variants, including the A8X and the A9X) for Apple (the  
7 "Apple Chips").<sup>4</sup>

8 48. TSMC similarly fabricates modems, CPUs, GPUs, FPGAs, and other chips for  
9 numerous other companies using its 16 and 20 nanometer finFET process (the "Other 16nm and  
10 20nm Chips").

11 49. Though TSMC does not publicly disclose all of its customers for its 16nm and 20nm  
12 node processes, on information and belief the Other 16nm and 20nm Chips are functionally  
13 identical to the Huawei Chips and the Apple Chips for purposes of this Complaint, are fabricated  
14 by TSMC using the same fabrication method, and have the same relevant structures.

15 50. For example, Dr. Cohen's reverse engineering analysis of the Apple Chips and the  
16 Huawei Chips (discussed further below) has revealed that those chips, fabricated at the same or  
17 similar nodes, contain the same relevant structures for purposes of this Complaint (including at  
18 least the metal layers).

19 51. Dr. Cohen's reverse engineering analysis of additional chips manufactured using  
20 TSMC's 16nm or 20nm nodes has revealed that those chips too contain the same relevant structures  
21 for purposes of this Complaint.

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27 \_\_\_\_\_  
28 <sup>4</sup> The Apple Chips are incorporated into the Apple iPhone 6 and iPhone 7 generation smart  
phones and tablets.

1           52.     TSMC’s 16 nanometer node interconnect technology is in all relevant ways identical  
2 to its 20 nanometer node interconnect technology, as they both share the same metal backend  
3 process.<sup>5</sup>

4           53.     On information and belief, it is industry practice that when a large chip fabricator  
5 like TSMC adopts a certain process for a specific node (such as a process for applying seed layers  
6 for metallic interconnects), it uses that same process for all chips fabricated at that same node.  
7

8           54.     Therefore, on information and belief, all Other 16nm and 20nm Node Chips have  
9 identical relevant structures for purposes of this Complaint.

10          55.     Hereinafter, the Huawei Chips, Apple Chips, Other 16nm and 20nm Chips, and  
11 other chips created by the AMAT Volta System as described in the Volta Animation will be referred  
12 to collectively as the “Accused Chips.”

13          56.     The Accused Chips comprise integrated circuits that comprise multiple-seed-layer  
14 structures.  
15

16          57.     HiSilicon designs, develops, and supplies the Huawei Chips for incorporation into  
17 Huawei’s mobile devices. Huawei incorporates the Huawei Chips it receives from HiSilicon into  
18 at least the Huawei P9 and Huawei Honor 8 Smartphones. HiSilicon works closely with TSMC on  
19 the design of the Huawei Chips:  
20

21                 **TSMC 16FF+ Manufactured**

22                 As mentioned earlier, the Kirin 950 is HiSilicon’s first TSMC 16FF+ manufactured mobile  
23 SoC. This also makes the Chinese vendor second in line after Apple’s to release mobile  
24 silicon based on the new manufacturing node.

25 <sup>5</sup> <http://www.tsmc.com/english/dedicatedFoundry/technology/16nm.htm>; *see also*  
26 <http://www.dailytech.com/TSMC+Hypes+Its+Upcoming+10+nm+Process+Amid+Struggles+to+Hit+Volume+at+16+nm/article37298.htm> (“TSMC’s strategy to achieve 16 nm production is  
27 controversial, as it’s built ‘on top of’ TSMC’s 20 nm process. It uses 16 nm  
28 transistors. However, for the backplane it uses 20 nm interconnects (bonding pads, electrical  
contacts, insulating layers, and metal layers).”).

1 HiSilicon explains that along with Apple they've been the two main lead partners of  
2 [TSMC], and both parties have been working closely together to try to improve the design  
3 and to tune the process. In fact, the company revealed that first mass production (also  
4 commonly named as risk production) started as early as last January. Over the following  
5 months both companies cooperated to sort out bugs and imperfections in the design (chip  
6 revisions) to go up from 20% yield in the earliest runs to up to 80% yields and qualified  
7 mass production this last August.<sup>6</sup>

8 58. Apple designed the Apple Chips which are made by TSMC for Apple. With respect  
9 to the design of its A8, Apple has explained:

10 iPod touch features an Apple-designed A8 chip built on 64-bit architecture. This desktop-  
11 class chip features GPU performance up to 10 times faster than the previous-generation  
12 iPod touch — so the graphics in your favorite games are more responsive and look more  
13 vivid than ever before — and CPU performance is up to six times faster. And you get the  
14 same great battery life, with up to 40 hours of music and 8 hours of video playback.<sup>7</sup>

15 The all-new A8 chip is our fastest yet. Its CPU and graphics performance are faster than  
16 on the A7 chip, even while powering a larger display and incredible new features. And  
17 because it's designed to be so power efficient, the A8 chip can sustain higher  
18 performance. . . . A8 uses an advanced 20-nanometer process. It's a remarkably small  
19 and efficient chip on which two billion transistors deliver incredible performance with up  
20 to 50 percent more energy efficiency than the A7 chip.<sup>8</sup>

21 59. With respect to the design of its A9 chips, Apple has explained:

22 The A9 chip brings a new level of performance and efficiency to iPhone 6s. Not only a  
23 faster experience, but a better one. The A9 chip is capable of gaming console-class  
24 graphics performance that makes games and other apps much richer and more immersive.

25 . . . The A9 chip is our third-generation chip with 64-bit architecture. It sits at the cutting  
26 edge of mobile chips, improving overall CPU performance by up to 70 percent compared  
27 to the previous generation. And boosting graphics performance by up to a staggering  
28 90 percent compared to the previous generation.<sup>9</sup>

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26 <sup>6</sup> <http://consumer.huawei.com/en/press/media-coverage/hw-462408.htm>

27 <sup>7</sup> <http://www.apple.com/ipod-touch/>

28 <sup>8</sup> <http://www.apple.com/iphone-6/technology/>

<sup>9</sup> <http://www.apple.com/iphone-6s/technology/>

1           60.     TSMC uses its 16 nanometer node finFET process to fabricate the A9 and A10  
2 processors.<sup>10,11</sup>

3           61.     With respect to the design of its A10 chips, Apple has explained:

4           iPhone 7 is supercharged by the most powerful chip ever in a smartphone. It's not just faster  
5 than any previous iPhone — it's also more efficient. That's because the A10 Fusion chip  
6 uses an all-new architecture that enables faster processing when you need it, and the ability  
7 to use even less power when you don't. And with the longest battery life ever in an iPhone,  
you can work at twice the speed of iPhone 6 and still enjoy more time between charges.

8           With an all-new four-core design, the A10 Fusion chip's CPU has two high-performance  
9 cores and two high-efficiency cores. The high-performance cores can run at up to 2x the  
10 speed of iPhone 6, while the high-efficiency cores are capable of running at just one-fifth  
the power of the high-performance cores. That means you get the best performance and  
11 efficiency when you need it.<sup>12</sup>

12           62.     Based in part on the allegations in paragraphs 49-53, above, as well as on other  
13 reports of collaboration between TSMC and its customers, on information and belief TSMC also  
14 cooperates with its customers for the Other 16nm and 20nm Chips, including by collaborating on  
15 chip design, coauthoring papers and articles, etc.

16           63.     In 2010, in an article titled "A New Enhancement Layer to Improve Copper  
17 Interconnect Performance," and published in the IEEE International Technology Conference,  
18 TSMC reported that the use of cobalt as a seed/enhancement layer between a PVD tantalum barrier  
19 layer and a copper seed layer would improve copper wetting on the barrier layer, improve  
20 interconnect quality, electrical performance, reliability, and maximize gap fill in integrated circuits  
21 ("TSMC's IEEE Paper").<sup>13</sup>

22  
23  
24 <sup>10</sup> <http://www2.techinsights.com/1/8892/2015-09-28/zxx9c;>

25 <sup>11</sup> [http://appleinsider.com/articles/16/07/11/apple-chip-builder-tsmc-expected-to-see-record-q3-](http://appleinsider.com/articles/16/07/11/apple-chip-builder-tsmc-expected-to-see-record-q3-on-a10-chips)  
[https://en.wikipedia.org/wiki/Apple\\_A10;](https://en.wikipedia.org/wiki/Apple_A10)  
[http://appleinsider.com/articles/16/06/30/tsmc-expected-to-net-big-revenue-boost-on-apple-a10-](http://appleinsider.com/articles/16/06/30/tsmc-expected-to-net-big-revenue-boost-on-apple-a10-chips-for-iphone-7)  
26 [chips-for-iphone-7](http://appleinsider.com/articles/16/06/30/tsmc-expected-to-net-big-revenue-boost-on-apple-a10-chips-for-iphone-7)

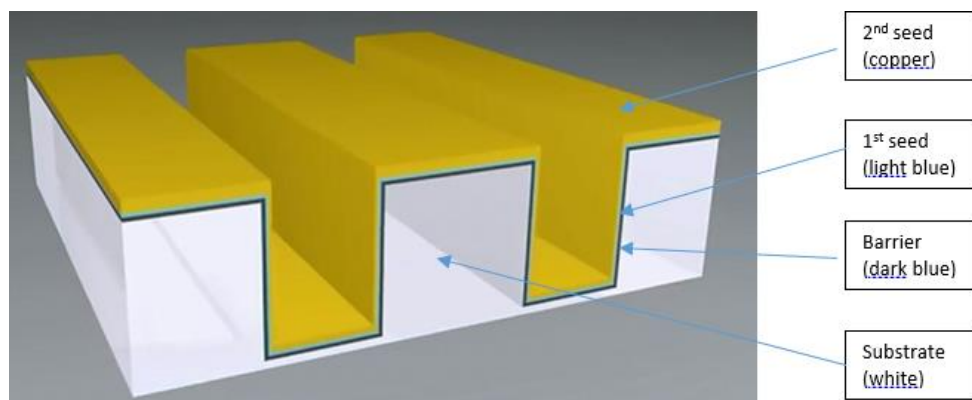
27 <sup>12</sup> <https://www.apple.com/iphone-7/>

28 <sup>13</sup> [http://ieeexplore.ieee.org/xpl/login.jsp?tp=&arnumber=5510762&url=http%3A%2F%2Fieeexplore.ieee.org%2Fxppls%2Fabs\\_all.jsp%3Farnumber%3D5510762](http://ieeexplore.ieee.org/xpl/login.jsp?tp=&arnumber=5510762&url=http%3A%2F%2Fieeexplore.ieee.org%2Fxppls%2Fabs_all.jsp%3Farnumber%3D5510762)

1           64. To achieve this integrated circuit design in its 20 nanometer and 16 nanometer node  
2 technologies, as reported in TSMC's IEEE Paper, TSMC on information and belief utilizes  
3 equipment supplied to it by AMAT, including the AMAT Volta System.<sup>14</sup>

4           65. On information and belief, the method utilized by TSMC to manufacture the  
5 Accused Chips and the resulting structure of the Accused Chips themselves are consistent with the  
6 methods and structures as explained by TSMC in its IEEE Paper, as explained by AMAT in its  
7 marketing materials concerning the AMAT Volta System, and as explained by AMAT in an  
8 animation it produced concerning the AMAT Volta System (the "Volta Animation") as depicted  
9 below.  
10

11           66. As shown here, the resulting 20 nanometer and 16 nanometer devices fabricated by  
12 TSMC using the AMAT Volta System contain a multiple seed layer structure comprising a  
13 patterned insulating layer formed on a substrate, a tantalum barrier layer over the substrate, a first  
14 seed layer comprising cobalt, a second seed layer comprising copper, and an electroplated metallic  
15 layer of copper disposed over the second seed layer:<sup>15</sup>  
16



24

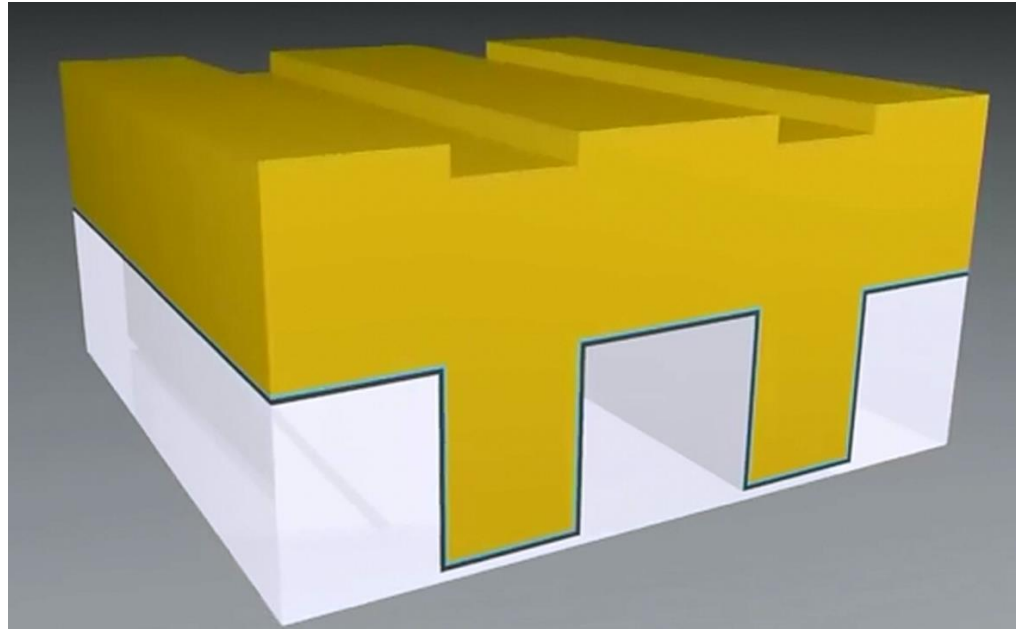
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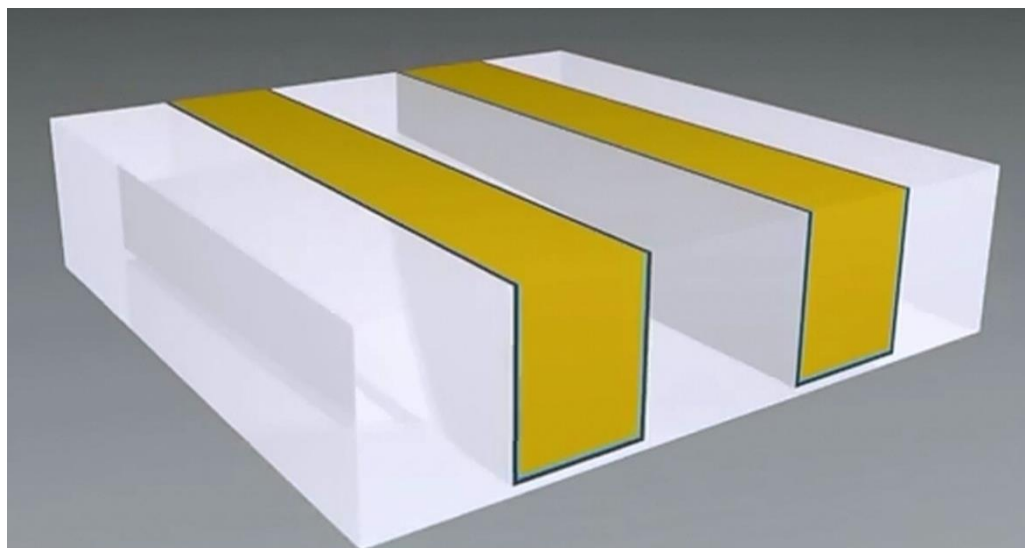
27 <sup>14</sup> <http://www.appliedmaterials.com/products/endura-volta-cvd-cobalt>

28 <sup>15</sup> See "Volta Animation," appliedchannel, <https://www.youtube.com/watch?v=EcWdzKRK2dk>.

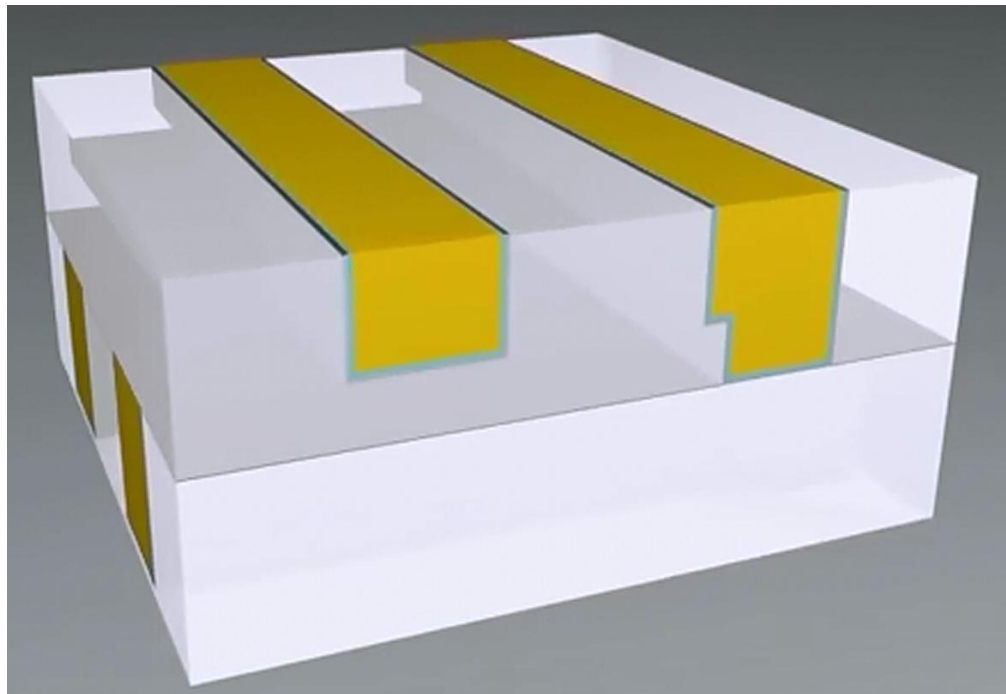
1           67.     After the barrier, first seed layer and second seed layer are formed over the substrate,  
2 electroplated copper is disposed over the second seed layer over the openings and the field, as  
3 depicted below.



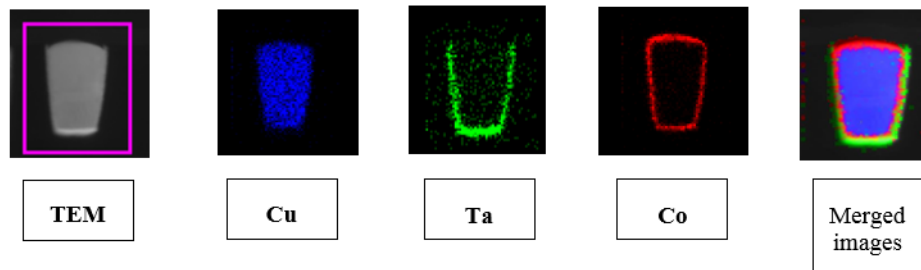
15           68.     After the electroplated copper is disposed over the openings and the field, the  
16 electroplated copper overlying the field, the first and second seed layers overlying the field, and the  
17 barrier layer overlying the field are all substantially removed by a polishing technique. The  
18 resulting interconnect is as is depicted below.



1 69. Multiple levels of interconnects are often stacked one on top of another, which is  
 2 the case with the Accused Chips, as depicted below.



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 7  
 8  
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 10  
 11  
 12  
 13  
 14  
 15 70. Confirming the existence of the structure depicted above in the Accused Chips, the  
 16 images below depict actual cross-sections of interconnects in the Apple Chips and Huawei Chips  
 17 obtained via reverse engineering.



18  
 19  
 20  
 21  
 22  
 23  
 24 71. The presence of a cobalt (“Co”) seed layer in these cross-sections confirms the use  
 25 in the Accused Chips of the multiple-seed-layer process described above.

1           72.     The images are unable to depict a distinct copper seed layer on top of the cobalt seed  
2 layer because electroplating merges the copper seed layer with the electroplated copper, as  
3 illustrated in paragraphs 59-60 and 63, above.

4           73.     However, on information and belief, achieving the copper metallization depicted in  
5 the cross-section images is accomplished by first applying a copper seed layer on top of the cobalt  
6 seed layer prior to electroplating, as illustrated in paragraphs 59 and 60.

7           74.     On information and belief, other AMAT Customers who purchase and use the  
8 AMAT Volta system according to the Volta Animation also create chips using the multiple-seed-  
9 layer process described above, which are functionally equivalent for purposes of infringement to  
10 the Apple Chips, Huawei Chips, and Other 16nm and 20nm Chips.

11  
12                   **BACKGROUND INFORMATION CONCERNING DEFENDANTS' ACTS OF**  
13                   **INFRINGEMENT**

14           75.     All preceding paragraphs are incorporated by reference as if fully set forth herein.

15           76.     The Accused Chips meet or embody the limitations of at least one claim of each of  
16 the patents-in-suit, as described further below in Counts I–IV.

17           77.     The AMAT Volta System employs the methods and produces Accused Chips that  
18 meet the limitations of at least one claim of each of the patents-in-suit.

19           78.     The Defendants have infringed at least one claim of each of the patents-in-suit by  
20 making, using, selling, offering for sale within the United States and/or importing into the United  
21 States, the Accused Chips; or have induced infringement of the same.

22           79.     More specifically, on information and belief, Defendant AMAT designs, fabricates  
23 and sells the AMAT Volta System to TSMC and the other AMAT Customers, and instructs the  
24 AMAT Customers how to use the AMAT Volta System in an infringing way (as shown in the Volta  
25 Animation). TSMC and other AMAT Customers use the AMAT Volta System to perform the  
26 Animation). TSMC and other AMAT Customers use the AMAT Volta System to perform the  
27 Animation). TSMC and other AMAT Customers use the AMAT Volta System to perform the  
28 Animation).



1 patented methods and make the Accused Chips for sale and/or importation in the United States.  
2 Further, on information and belief, AMAT uses the AMAT Volta System itself to make and use  
3 Accused Chips in the United States.

4 80. Further, on information and belief, Defendant TSMC makes the Huawei Chips for  
5 Huawei, then offers to sell and sells the Huawei Chips for use in the United States.  
6

7 81. Huawei imports, offers to sell, and/or sells devices containing the Huawei Chips  
8 (such as the Huawei P9 and Huawei Honor 8 Smartphones) in the United States.

9 82. On information and belief, Defendant TSMC makes the Apple Chips for Apple, then  
10 offers to sell and sells the Apple Chips for use in the United States.

11 83. Apple imports, offers to sell, and sells devices containing the Apple Chips (such as  
12 the Apple iPhone 6 and iPhone 6 Plus, iPhone 6S and iPhone 6S Plus, iPhone SE, iPad Touch, iPad  
13 Pro (12.9”), iPad Pro Mini (9.7”), iPhone 7 and iPhone 7 Plus) in the United States.  
14

15 84. On information and belief, Defendant TSMC makes the Other 16nm and 20nm  
16 Chips for its other customers, then offers to sell and sells the Other 16nm and 20nm Chips for use  
17 in the United States.

18 85. TSMC’s customers and their affiliates—including but not limited to Apple, Huawei,  
19 other equipment manufacturers, chip designers, and chipset makers—import, offer to sell, and/or  
20 sell devices containing the Other 16nm and 20nm Chips (including the Apple devices listed above,  
21 the Huawei devices listed above, and Huawei’s Google Nexus 6P) in the United States.  
22

23 86. On information and belief, Huawei uses devices containing the Accused Chips in  
24 the United States, during testing, demonstrations, and the like.

25 87. On information and belief, Apple uses devices containing the Accused Chips in the  
26 United States, during testing, demonstrations, and the like.  
27

1           1)       **DEFENDANTS' DIRECT INFRINGEMENT**

2                    *i. AMAT'S Direct Infringement*

3           88.     All preceding paragraphs are incorporated by reference as if fully set forth herein.

4           89.     AMAT directly infringes at least one claim of each of the patents-in-suit, either  
5 literally or under the doctrine of equivalents, by employing the patented methods within the United  
6 States to make and use Accused Chips.

7                    *ii. TSMC'S Direct Infringement*

8           90.     All preceding paragraphs are incorporated by reference as if fully set forth herein.

9           91.     TSMC directly infringes at least one claim of each of the patents-in-suit, either  
10 literally or under the doctrine of equivalents, by selling and/or offering for sale within the United  
11 States the Accused Chips.

12           92.     On information and belief, TSMC collaborates with its customers in the United  
13 States regarding the design of the Accused Chips.

14           93.     On information and belief, TSMC conducts marketing efforts related to the Accused  
15 Chips in the United States.

16           94.     On information and belief, TSMC engages in pricing and contractual negotiations  
17 regarding the Accused Chips with customers in the United States.

18           95.     On information and belief, TSMC receives purchase orders for Accused Chips in  
19 the United States.

20           96.     On information and belief, TSMC executes contracts for sale of the Accused Chips  
21 in the United States.

22           97.     Many of the Accused Chips are ultimately sold, offered for sale, and used in devices  
23 within the United States.

1           98. On information and belief, TSMC knows that many of the Accused Chips it sells its  
2 customers will ultimately be sold, offered for sale, and used in devices within the United States.

3                           *iii. Other AMAT Customers' Direct Infringement*

4           99. On information and belief, other AMAT Customers who make Accused Chips  
5 directly infringe at least one claim of each of the patents-in-suit, either literally or under the doctrine  
6 of equivalents, in the same or similar way as TSMC—by using the AMAT Volta System in an  
7 infringing manner within the United States, and/or by selling and offering for sale the Accused  
8 Chips in the United States.

9                           *iv. Huawei's Direct Infringement*

10           100. All preceding paragraphs are incorporated by reference as if fully set forth herein.

11           101. Huawei directly infringes at least at least one claim of each of the patents-in-suit  
12 under 35 U.S.C. 271(a) and 271(g), either literally or under the doctrine of equivalents, by making,  
13 using, selling, offering for sale within the United States, leasing, and/or importing into the United  
14 States, devices that incorporate the Accused Chips (including at least the Huawei P9, Huawei Honor  
15 8, and Google Nexus 6P Smartphones).

16           102. The Accused Chips made by the processes claimed in the asserted process claims of  
17 the patents-in-suit are not materially changed by subsequent processes prior to importation, use,  
18 sale, or offer for sale in the United States by Huawei.

19           103. As demonstrated by the cross-section images and other information above, Dr.  
20 Cohen's patented multiple-seed-layer structure, and benefits thereof, remain discernible and intact  
21 in the Accused Chips as sold.

22           104. The Accused Chips made by the processes claimed in the asserted process claims of  
23 the patents-in-suit do not become a trivial or nonessential component of another product prior to  
24 importation, use, sale, or offer for sale in the United States by Huawei.

1           105. As demonstrated by the cross-section images and other information above, Dr.  
2 Cohen's patented multiple-seed-layer structure, and benefits thereof, remain discernible and intact  
3 in the Accused Chips as sold.

4           106. The Accused Chips, which include central processing units, graphics processing  
5 units, modems, etc., are essential to the operation of the electronic devices, chipsets, and other  
6 products the Accused Chips are incorporated into.

7  
8                           *v. Other TSMC Customers' Direct Infringement*

9           107. All preceding paragraphs are incorporated by reference as if fully set forth herein.

10           108. TSMC's other customers—including Apple—who sell devices in the United States  
11 containing the Apple Chips or Other 16nm and 20nm Chips directly infringe at least one claim of  
12 each of the patents-in-suit under 35 U.S.C. 271(a) and 271(g), either literally or under the doctrine  
13 of equivalents, by making, using, selling, offering for sale within the United States, leasing, and/or  
14 importing into the United States, smart phones and other devices that incorporate the Accused  
15 Chips (including at least the Apple iPhone 6 and iPhone 6 Plus, iPhone 6S, 6S Plus, iPhone SE,  
16 iPad Touch, iPad Pro (12.9"), iPad Pro Mini (9.7"), iPhone 7 and iPhone 7 Plus).

17  
18           109. The Accused Chips made by the processes claimed in the asserted process claims of  
19 the patents-in-suit are not materially changed by subsequent processes prior to importation, use,  
20 sale, or offer for sale in the United States by Apple.

21  
22           110. As demonstrated by the cross-section images and other information above, Dr.  
23 Cohen's patented multiple-seed-layer structure, and benefits thereof, remain discernible and intact  
24 in the Accused Chips as sold.

25           111. The Accused Chips made by the processes claimed in the asserted process claims of  
26 the patents-in-suit do not become a trivial or nonessential component of another product prior to  
27 importation, use, sale, or offer for sale in the United States by TSMC's other customers.

1 112. As demonstrated by the cross-section images and other information above, Dr.  
2 Cohen's patented multiple-seed-layer structure, and benefits thereof, remain discernible and intact  
3 in the Accused Chips as sold.

4 113. The Accused Chips, which include central processing units, graphics processing  
5 units, modems, etc., are essential to the operation of the electronic devices, chipsets, and other  
6 products the Accused Chips are incorporated into.  
7

8 2) **DEFENDANTS' INDUCEMENT OF INFRINGEMENT**

9 *i. AMAT's Inducement of Infringement*

10 114. All preceding paragraphs are incorporated by reference as if fully set forth herein.

11 115. AMAT has had actual knowledge of the patents-in-suit since at least September  
12 2007.

13 116. Moreover, AMAT has referenced Dr. Cohen's '668 patent in no less than six patents  
14 and patent applications assigned to AMAT, including U.S. Patent Nos. 6,842,659, 6,936,906,  
15 6,916,398, 8,993,434, 9,768,060, and U.S. Patent Applications No. 20140046475A1.  
16

17 117. Moreover, AMAT has referenced Dr. Cohen's '226 patent in no less than four  
18 patents and patent applications assigned to AMAT, including U.S. Patent Nos. 6842659, 6936906,  
19 6916398, and U.S. Patent Applications No. 20140046475A1.  
20

21 118. Moreover, AMAT has referenced Dr. Cohen's '445 patent in no less than six patents  
22 and patent applications assigned to AMAT, including U.S. Patent Nos. 6,842,659, 6,936,906,  
23 6,916,398, 8,993,434, 9,768,060, and U.S. Patent Applications No. 20140046475A1.

24 119. Upon information and belief, AMAT knew of, or was willfully blind towards, its  
25 infringement of the patents-in-suit at least since it began developing, testing, and selling the AMAT  
26 Volta System.  
27

1           120. Since becoming aware of the patents-in-suit, AMAT's advertising, sales, and/or  
2 technical materials in relation to the AMAT Volta System (including the Volta Animation) have  
3 intentionally, actively, knowingly, and willfully contained and continue to contain instructions,  
4 directions, suggestions, and/or invitations that intentionally, actively, and knowingly invite, entice,  
5 lead on, influence, encourage, prevail on, move by persuasion, and/or cause the public, AMAT's  
6 distributors, retailers, and customers (including TSMC) to thereby directly infringe (via § 271(a)  
7 and/or § 271(g)) at least one claim of each of the patents-in-suit, either literally or under the doctrine  
8 of equivalents.  
9

10           121. On information and belief, AMAT has collaborated with its customers, including  
11 TSMC, on the operation of the AMAT Volta System and manufacture of the Accused Chips. Since  
12 becoming aware of, or being willfully blind towards, its infringement of the patents-in-suit, AMAT  
13 was willfully blind or knew that the public's, the distributors', the retailers', and/or the customers'  
14 use of the AMAT Volta System, or using, importing, selling, and/or offering to sell the Accused  
15 Chips, directly infringes (via § 271(a) and/or § 271(g)), either literally or under the doctrine of  
16 equivalents, at least one claim of each of the patents-in-suit.  
17

18           122. For at least these reasons, as well as others that may be revealed through discovery,  
19 AMAT is liable for inducing infringement (via § 271(a) and/or § 271(g)) of the patents-in-suit,  
20 either literally or under the doctrine of equivalents.  
21

22           *ii. TSMC's Inducement of Infringement*

23           123. All preceding paragraphs are incorporated by reference as if fully set forth herein.

24           124. TSMC has had actual knowledge of the '668 patent since as early as July 23, 2004,  
25 including representative claim charts and infringement analyses for the '668 patent.

26           125. Moreover, TSMC has referenced Dr. Cohen's '668 patent in no less than 15 patents  
27 and patent applications assigned to TSMC, including U.S. Patent Nos. 6,806,192, 6,943,111,  
28

1 7,067,409, 7,215,024, 7,265,038, 7,378,744, 8,277,619, and U.S. Patent Applications Nos.  
2 20040147104, 20040157431, 20050029665, 20050110147, 20050250320, 20050263902,  
3 20060216916, and 20070010080. Additionally, TSMC has had actual knowledge of the '226 patent  
4 since as early as May 1, 2006, including representative claim charts and infringement analyses for  
5 the '226 patent.  
6

7 126. Additionally, TSMC has had actual knowledge of the application that matured into  
8 the '052 patent (U.S. Application No. 2007-0117379) since as early as May 1, 2006, and then the  
9 '052 patent itself since as early as June 29, 2007.

10 127. Moreover, TSMC has referenced Dr. Cohen's '052 patent in at least two patents  
11 assigned to TSMC, including U.S. Patent Nos. 7,704,886 and 8,252,690.

12 128. Additionally, TSMC has had actual knowledge of the application that matured into  
13 the '445 patent (that is, U.S. Application No. 11/654,478) since as early as June 29, 2007.

14 129. Upon information and belief, TSMC knew of, or was willfully blind towards, its  
15 infringement of the patents-in-suit at least since it began fabricating Huawei Chips, Apple Chips  
16 and Other 16nm and 20nm Chips.  
17

18 130. Since becoming aware of, or being willfully blind towards, its infringement of the  
19 patents-in-suit, TSMC has continued to intentionally, actively, and knowingly make, use, sell, offer  
20 to sell, and/or import one or more of the Accused Chips through its retailers, resellers, and  
21 distributors, as well as in other ways.  
22

23 131. Since becoming aware of the patents-in-suit, TSMC's advertising, sales, and/or  
24 technical materials in relation to the Accused Chips have intentionally, actively, knowingly, and  
25 willfully contained and continue to contain instructions, directions, suggestions, and/or invitations  
26 that intentionally, actively, and knowingly invite, entice, lead on, influence, encourage, prevail on,  
27 move by persuasion, and/or cause the public, TSMC's distributors, retailers, and customers  
28

1 (including the related Huawei entities and Apple) to thereby directly infringe (via § 271(a) and/or  
2 § 271(g)) at least one claim of each of the patents-in-suit, either literally or under the doctrine of  
3 equivalents.

4 132. TSMC has collaborated with its customers, including Apple and Huawei, on the  
5 design of the Accused Chips. Since becoming aware of, or being willfully blind towards, its  
6 infringement of the patents-in-suit, TSMC was willfully blind or knew that the public's, the  
7 distributors', the retailers', and/or the customers' using, importing, selling, and/or offering to sell  
8 the Accused Chips directly infringe (via § 271(a) and/or § 271(g)), either literally or under the  
9 doctrine of equivalents, at least one claim of each of the patents-in-suit.

10 133. For at least these reasons, as well as others that may be revealed through discovery,  
11 TSMC is liable for inducing infringement (via § 271(a) and/or § 271(g)) of the patents-in-suit,  
12 either literally or under the doctrine of equivalents.  
13

14  
15 *iii. Huawei's Inducement of Infringement*

16 134. All preceding paragraphs are incorporated by reference as if fully set forth herein.

17 135. Huawei has had actual knowledge of the patents in suit since at least as early of the  
18 filing or service of the Original Complaint in this case.

19 136. Huawei has had knowledge before at least some of its infringing acts that Dr.  
20 Cohen's patented processes were used to make Huawei Chips and Other 16nm and 20nm Chips.

21 137. Upon information and belief, Huawei knew of, or was willfully blind towards, its  
22 infringement of the patents-in-suit at least since the filing or service of the Original Complaint.

23 138. Since becoming aware of, or being willfully blind towards, its infringement of the  
24 patents-in-suit, Huawei has continued to intentionally, actively, and knowingly make, use, sell,  
25 offer to sell, and/or import one or more of the Huawei Chips and Other 16nm and 20nm Chips  
26 through its retailers, resellers, and distributors, as well as in other ways.  
27



1           139. Since becoming aware of the patents-in-suit, Huawei’s advertising, sales, and/or  
2 technical materials in relation to the Huawei Chips and Other 16nm and 20nm Chips have  
3 intentionally, actively, knowingly, and willfully contained and continue to contain instructions,  
4 directions, suggestions, and/or invitations that intentionally, actively, and knowingly invite, entice,  
5 lead on, influence, encourage, prevail on, move by persuasion, and/or cause the public, Huawei’s  
6 distributors, subsidiaries, retailers, and customers to thereby directly infringe (via § 271(a) and/or  
7 § 271(g)) at least one claim of each of the patents-in-suit, either literally or under the doctrine of  
8 equivalents.  
9

10           140. For at least these reasons, as well as others that may be revealed through discovery,  
11 Huawei is liable for inducing infringement (via § 271(a) and/or § 271(g)) of the patents-in-suit,  
12 either literally or under the doctrine of equivalents.  
13

14                           **COUNT I: INFRINGEMENT OF THE ’668 PATENT**

15           141. All preceding paragraphs are incorporated by reference as if fully set forth herein.

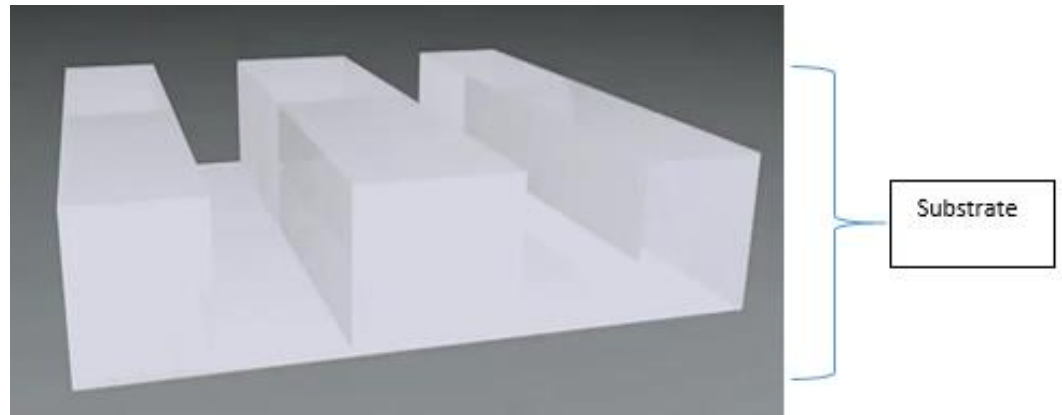
16           142. The Defendants have infringed at least one claim of the ’668 patent by performing  
17 the acts of infringement described above with respect to the AMAT Volta System and Accused  
18 Chips.

19           143. Each of the Accused Chips is fabricated by AMAT, TSMC, or other AMAT  
20 Customers using the same relevant fabrication method, and producing the same relevant chip  
21 structure, as explained in the Volta Animation, and as described above. As such, the Accused Chips  
22 meet each limitation of at least one claim of the ’668 patent.  
23

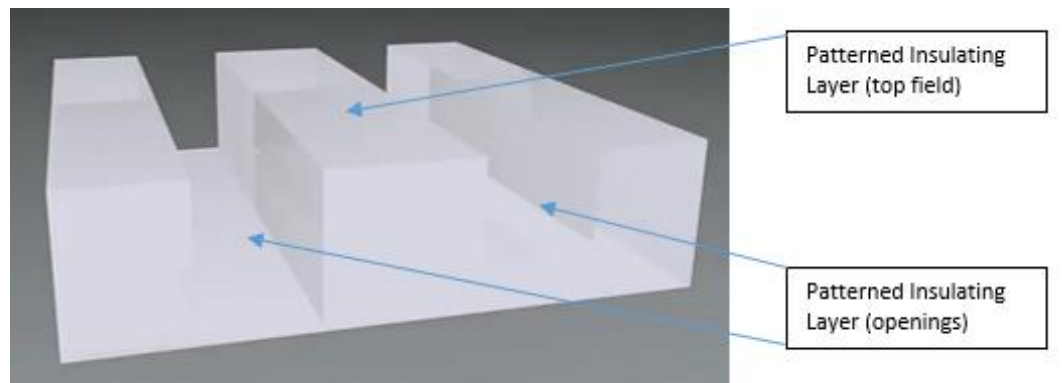
24           144. By way of example and not limitation, each of the Accused Chips meets or embodies  
25 every limitation of claim 26 (dependent of claim 1) of the ’668 patent:

26                   a. a substrate, as depicted below:  
27  
28

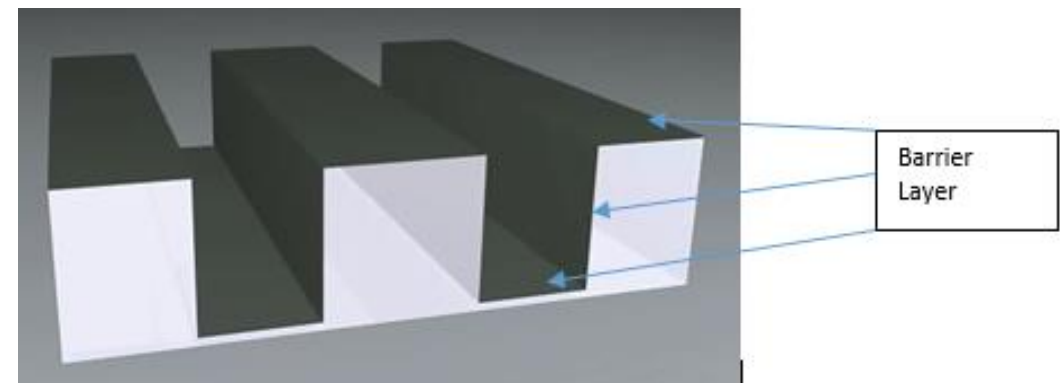
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b. a patterned insulating layer formed on said substrate, said patterned insulating layer including at least one opening and a top field surface surrounding said at least one opening, as depicted below:

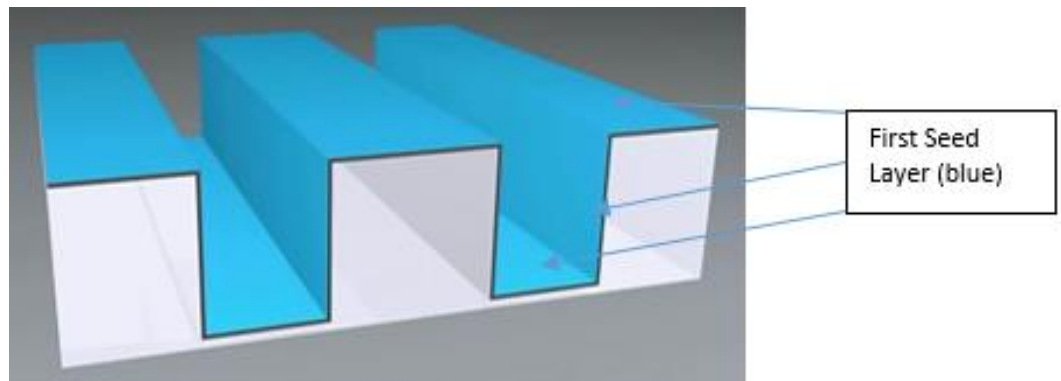


c. a barrier layer disposed over said patterned insulating layer including over inside surfaces of the at least one opening, as depicted below:



1 In the case of the Accused Chips, tantalum nitride is used for the barrier layer and is  
 2 applied through a PVD process.

3  
 4 d. a first seed layer disposed over the barrier layer, said first seed layer  
 5 comprising a substantially conformal seed layer whose thickness on the sidewalls  
 6 of the opening (at about mid-depth) is about 25-100% of its thickness on the field,  
 7 as depicted below:

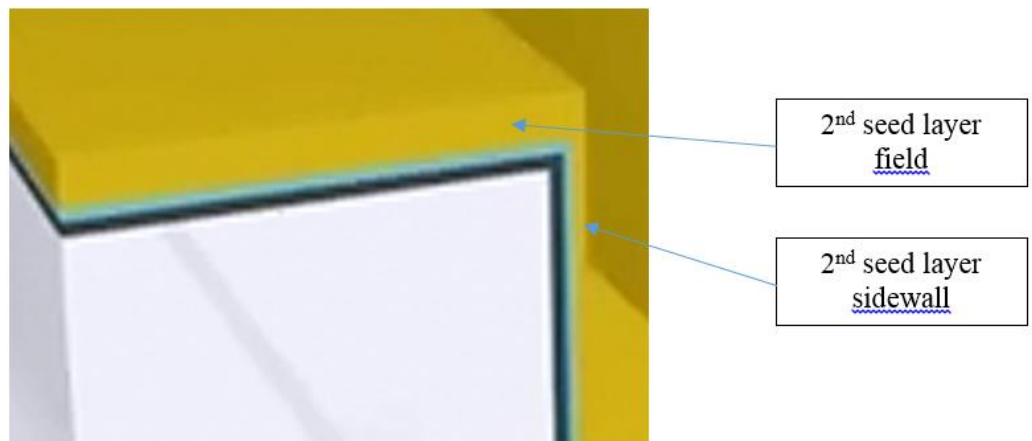
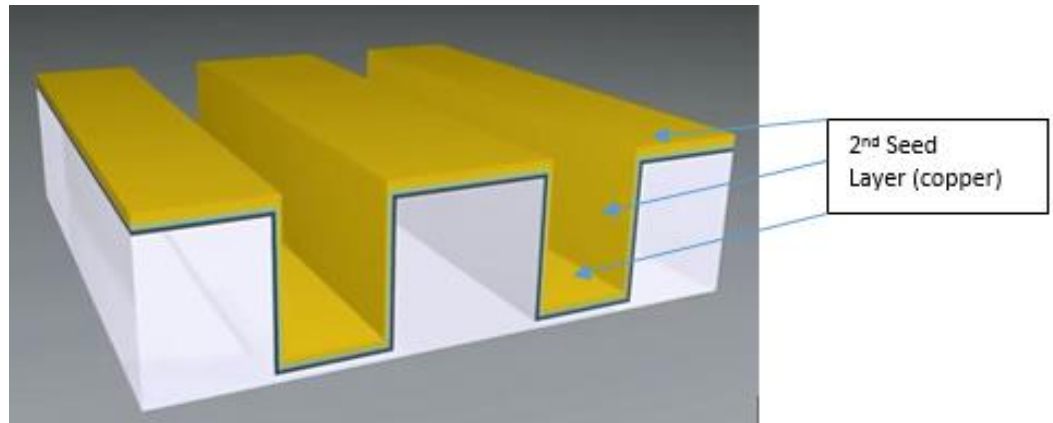


14 A first conformal layer of cobalt is applied over the barrier layer through a CVD process.  
 15 Because it is a conformal layer and applied through a CVD process, the thickness of the cobalt  
 16 layer on the sidewalls of the opening (at about mid-depth) is about 25-100% of its thickness on the  
 17 field.<sup>16</sup>

18  
 19 e. a second seed layer disposed over the first seed layer, said second seed layer  
 20 comprising a substantially non-conformal seed layer whose thickness on the  
 21 sidewalls of the opening (at about mid-depth) is less than about 25% of its thickness  
 22 on the field, and wherein said second seed layer being thicker than said first seed  
 23 layer over the field, as depicted below:

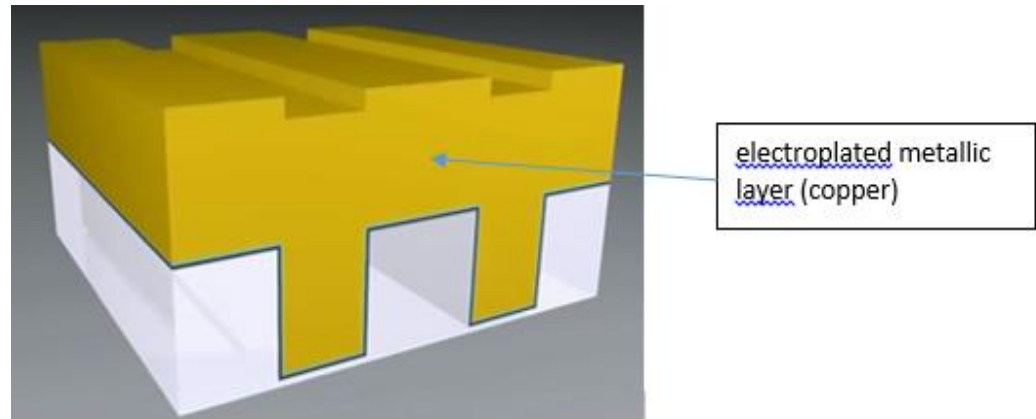
24  
 25  
 26  
 27 <sup>16</sup> See generally “Conformal CVD Co Deposition for Enhancement of Cu Gapfill Application,”  
 28 ADMETA Conference 2008, Tokyo, Japan (-5001 Case, Dkt. No. 31-6).

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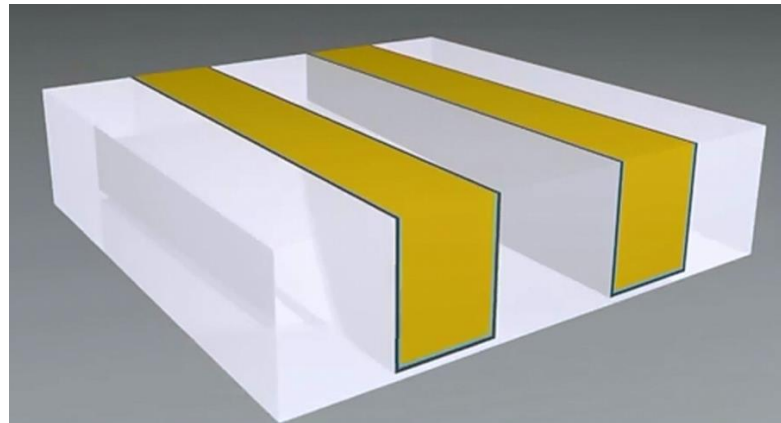
As is now well known in the art, at the geometries found in the accused chips, an optimized PVD copper seed layer at the 2x nanometer node and beyond will result in sidewall coverage at midpoint of about 13% to 15% of the thickness on the field, and certainly less than 25% of the thickness on the field.

f. an electroplated metallic layer disposed over the second seed layer, wherein the electroplated metallic layer comprises a material selected from a group consisting of Cu, Ag, or alloys comprising one or more of these metals, as depicted below:



8  
9 After the second substantially non-conformal seed layer is applied through a PVD process,  
10 an electroplated metallic layer of copper is disposed over the second seed layer in the openings and  
11 on the field, filling the openings.

12  
13 g. (claim 26) A metallic interconnect fabricated by using the multiple seed layer  
14 structure of claim 1, wherein the electroplated metallic layer overlying the opening  
15 and overlying the field, and the first and second seed layers overlying the field, and  
16 the barrier layer overlying the field, are substantially removed by a removal  
17 technique, said removal technique comprises one or more of a mechanical polishing  
18 technique, a chemical mechanical polishing technique, a wet etching technique, and  
19 a dry etching technique, as depicted below:



25 As explained in the Volta Animation, after copper is used to fill the openings and applied  
26 over the field through electroplating, the copper over the field and the barrier layer and first and  
27 second seed layers over the field are removed using a polishing technique.  
28

**COUNT II: INFRINGEMENT OF THE '226 PATENT**

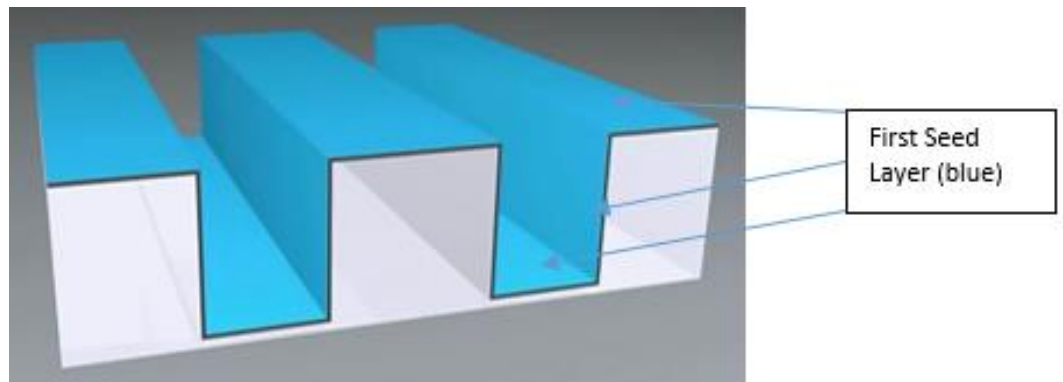
123. All preceding paragraphs are incorporated by reference as if fully set forth herein.

124. The Defendants have infringed at least one claim of the '226 patent by performing the acts of infringement described above with respect to the AMAT Volta System and the Accused Chips.

125. Each of the Accused Chips is fabricated by AMAT, TSMC, or other AMAT Customers using the same relevant fabrication method, and producing the same relevant chip structure, as explained in the Volta Animation, and as described above. As such, the Accused Chips embody at least one claim of the '226 patent.

126. By way of example and not limitation, each of the Accused Chips meets or embodies every limitation of at least claim 1 of the '226 patent in that each of the Accused Chips is fabricated using a method as recited in claim 1 by:

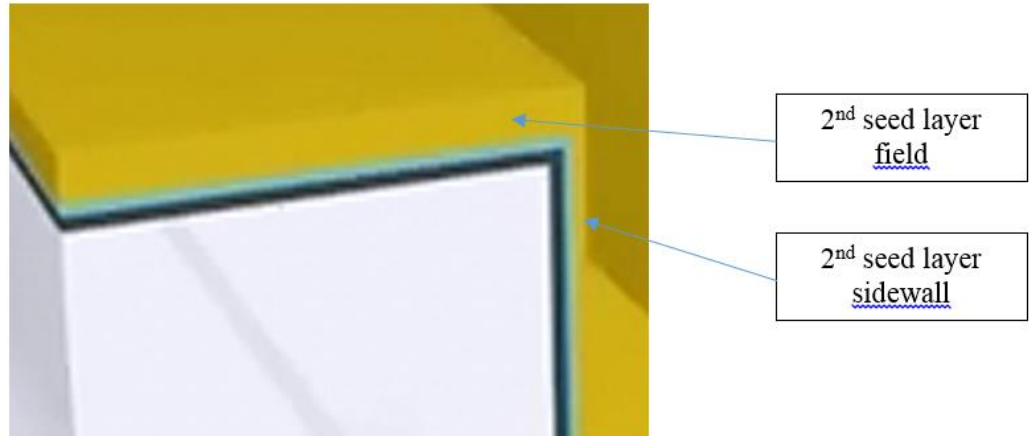
- a. depositing a substantially conformal seed layer over the field and inside surfaces of the at least one opening;



A substantially conformal layer of cobalt is deposited over the field and inside surfaces of at least one opening layer through a CVD process.

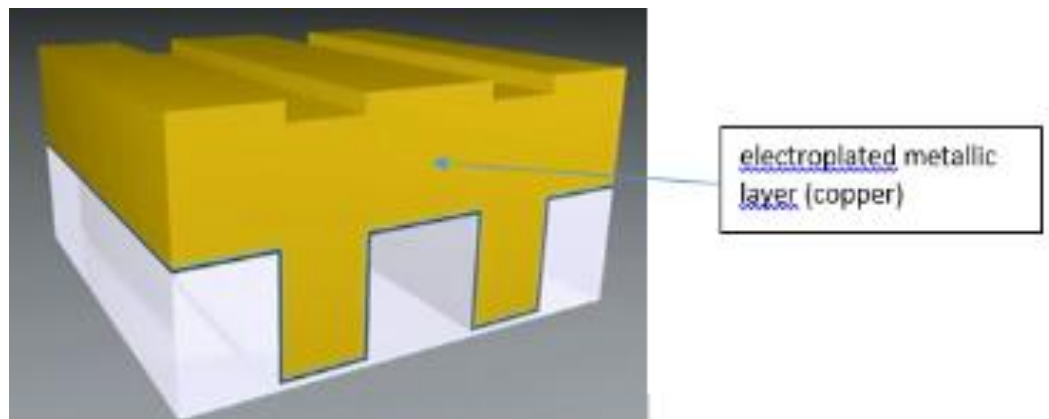
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b. depositing a substantially non-conformal seed layer over the substantially conformal seed layer, said substantially non-conformal seed layer being thicker than said substantially conformal seed layer over the field, wherein the substantially conformal and the substantially non-conformal seed layers do not seal the at least one opening; and



As depicted above and on information and belief, an optimized PVD copper seed layer at the 2x nanometer node and beyond will result in thickness over the field far greater than that of a substantially conformal CVD seed layer. Further, as depicted in the Volta Animation, the substantially conformal and the substantially non-conformal seed layers do not seal the at least one opening.

c. electroplating a metallic layer over the substantially non-conformal seed layer, wherein the electroplated metallic layer comprises a material selected from a group consisting of Cu, Ag, or alloys comprising one or more of these metals.



1 After the substantially non-conformal seed layer is applied through a PVD process, an  
2 electroplated metallic layer of copper (i.e. “Cu”) is disposed over the substantially non-conformal  
3 seed layer.

4 **COUNT III: INFRINGEMENT OF THE '052 PATENT**

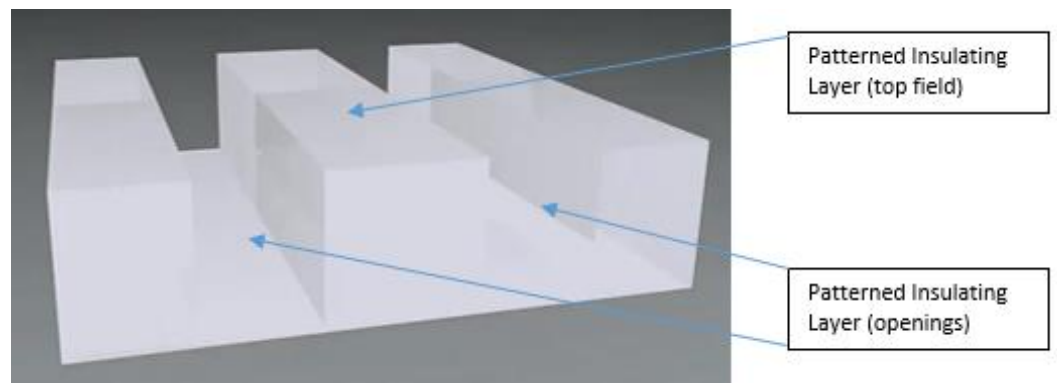
5 127. All preceding paragraphs are incorporated by reference as if fully set forth herein.

6 128. The Defendants have infringed at least one claim of the '052 patent by performing  
7 the acts of infringement described above with respect to the Accused Chips.

8 129. Each of the Accused Chips is fabricated by AMAT, TSMC, or other AMAT  
9 Customers using the same relevant fabrication method, and producing the same relevant chip  
10 structure, as explained in the Volta Animation, and as described above. As such, Accused Chips  
11 embody at least one claim of the '052 patent.

12 130. By way of example and not limitation, each of the Accused Chips meets or embodies  
13 every limitation of at least claim 4 of the '052 patent in that each of the Accused Chips is fabricated  
14 using a method as recited in claim 4 by:

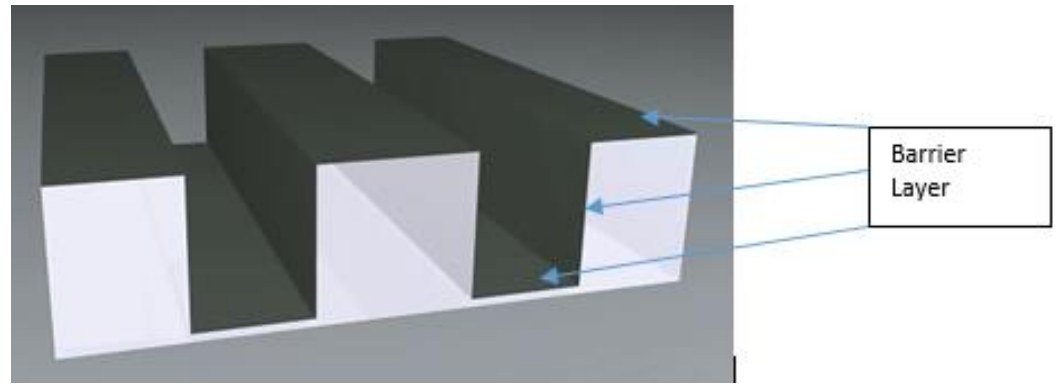
15  
16 a. forming a patterned insulating layer on a substrate, the patterned insulating  
17 layer including at least one opening and a field surrounding the at least one opening,  
18 as depicted below;



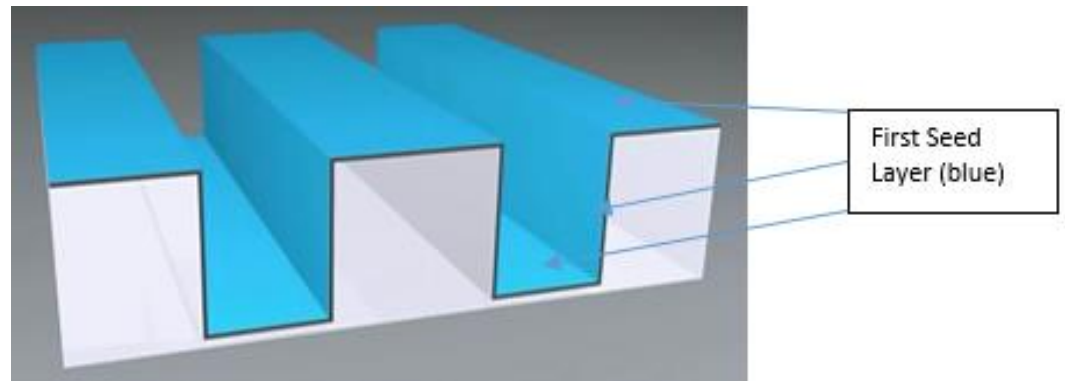
25 b. depositing a barrier layer over the field and inside surfaces of the at least one  
26 opening, as depicted below;



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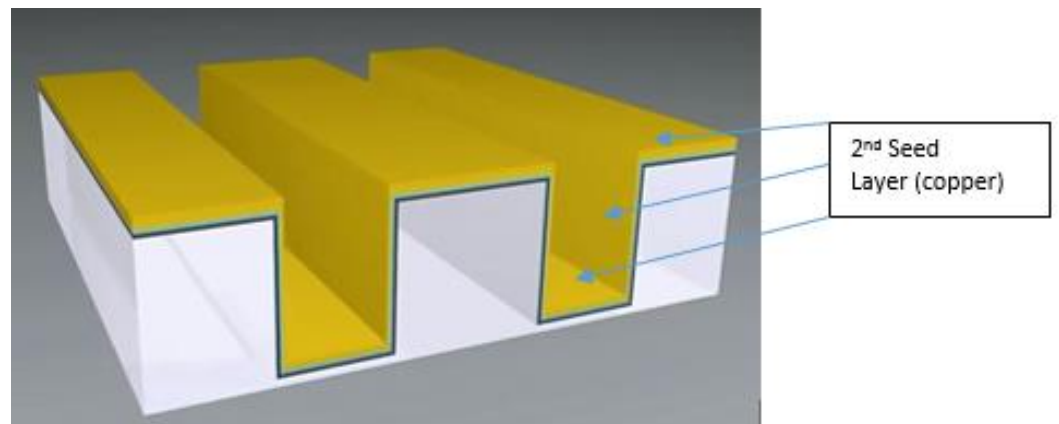


c. chemical vapor depositing a first seed layer over the barrier layer, as depicted below;

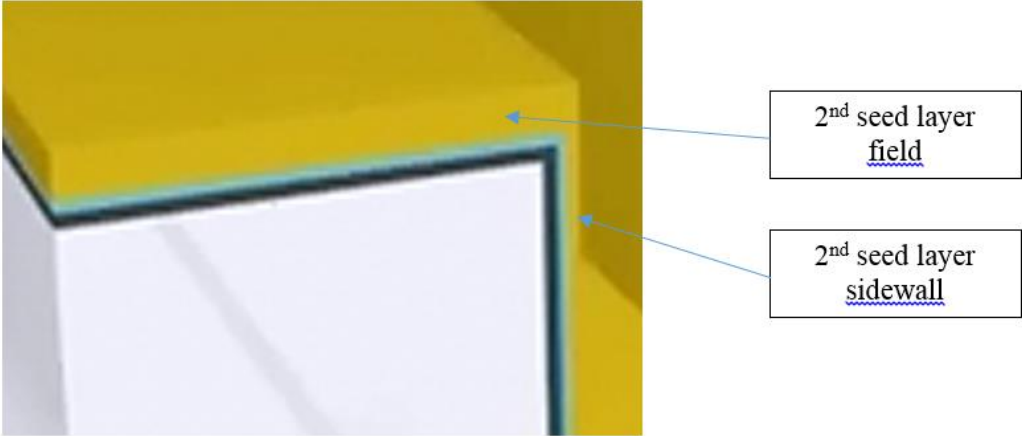


A first seed layer is deposited by a CVD technique over the barrier layer.

d. physical vapor depositing a second seed layer over the first seed layer, wherein the second seed layer is thicker than the first seed layer over the field, as depicted below; and

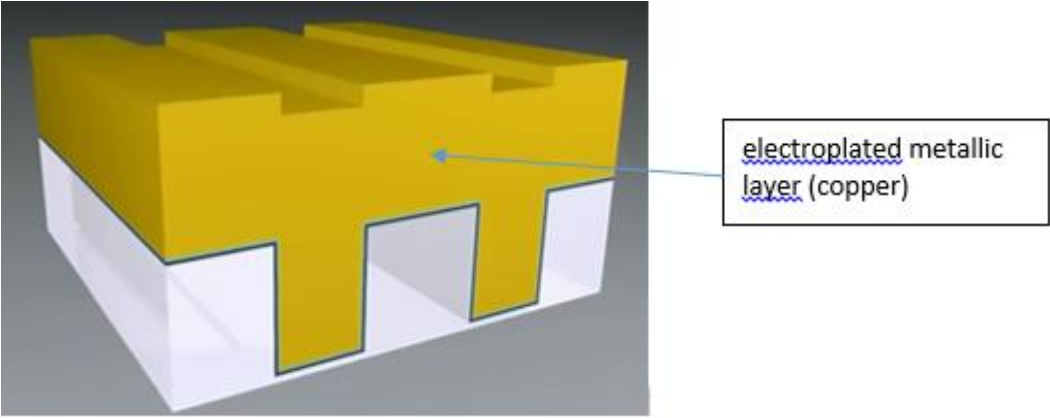


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A second seed layer is deposited by a PVD technique over the first seed layer. The second seed layer is thicker than the first seed layer over the field.

e. filling the at least one opening by electroplating a metallic layer comprising copper or a copper alloy over the two seed layers, as depicted below.



The openings are filled by electroplating copper over the two seed layers.

**COUNT IV: INFRINGEMENT OF THE '445 PATENT**

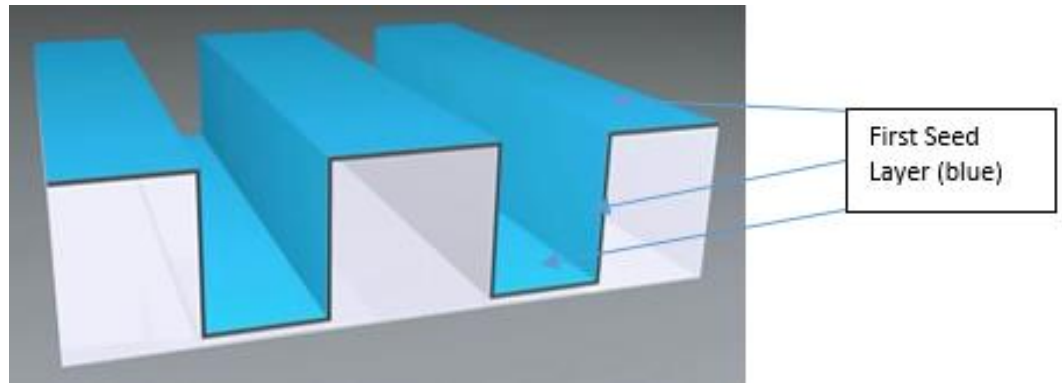
131. All preceding paragraphs are incorporated by reference as if fully set forth herein.

132. The Defendants have infringed at least one claim of the '445 patent by performing the acts of infringement described above with respect to the Accused Chips.

1           133. Each of the Accused Chips is fabricated by AMAT, TSMC, and other AMAT  
2 Customers using the same relevant fabrication method, and producing the same relevant chip  
3 structure, as explained in the Volta Animation, and as described above. As such, the Accused Chips  
4 embody at least one claim of the '445 patent.

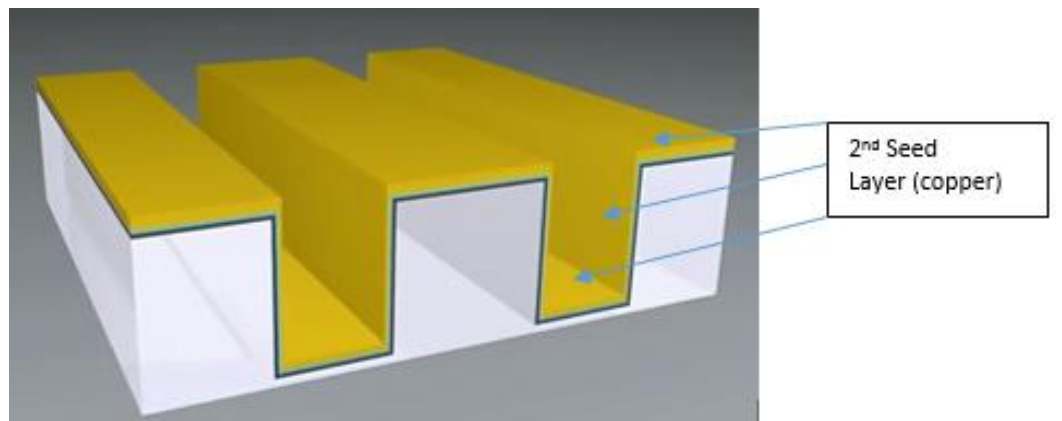
5  
6           134. By way of example and not limitation, each of the Accused Chips meets or embodies  
7 every limitation of at least claim 18 of the '445 patent in that each of the Accused Chips is fabricated  
8 using a method as recited in claim 18 by:

9           a. utilizing a CVD chamber capable of depositing a CVD seed layer over the  
10 sidewalls of the at least one opening;



17           A CVD chamber is used to deposit a first seed layer over the sidewalls of at least one  
18 opening.

19  
20           b. utilizing a PVD chamber capable of depositing a PVD seed layer over the  
21 substrate;



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A PVD chamber is used to deposit a second seed layer over the substrate.

- c. configuring an automatic controller with recipe information, the recipe information including deposition sequence, process and timing parameters for operation of the CVD chamber and the PVD chamber;

On information and belief, use of the AMAT Volta system requires at least one automatic controller containing recipe information which includes deposition sequence, process and timing parameters for operation of the CVD chamber and the PVD chamber.

- d. operating the automatic controller in accordance with the recipe information to cause the CVD chamber to deposit a CVD first seed layer over the field and the sidewalls of the at least one opening;

On information and belief, as shown in the Volta animation cited above, the said at least one automatic controller is operated in accordance with the recipe information to cause the CVD chamber to deposit a CVD first seed layer over the field and the sidewalls of the at least one opening.

- e. operating the controller in accordance with the recipe information to deposit in the PVD chamber a second seed layer over the first seed layer; and

On information and belief, as shown in the Volta animation cited above, the said at least one automatic controller is operated in accordance with the recipe information to cause the PVD chamber to deposit a second seed layer over the first seed layer and opening.

- f. operating the controller in accordance with the recipe information to stop the deposition of the first and second seed layers prior to sealing the at least one opening, thereby leaving enough room for electroplating inside the at least one opening.

On information and belief, as shown in the Volta animation cited above, the said at least one automatic controller is operated in accordance with the recipe information to stop the deposition of the first and second seed layers prior to sealing the at least one opening, thereby leaving enough room for electroplating inside the at least one opening.

**DAMAGES**

1  
2 135. The Defendants’ acts of infringement of the patents-in-suit as alleged above have  
3 injured Dr. Cohen and thus Dr. Cohen is entitled to recover damages which in no event can be less  
4 than a reasonable royalty, including his costs, and pre-judgment and post-judgment interest  
5 pursuant to 35 U.S.C. § 284.  
6

7 **WILLFUL INFRINGEMENT**

8 **A. Willful Infringement by AMAT**

9 136. AMAT has infringed the ’668, ’226, ’052, and ’445 patents despite an  
10 objectively high likelihood that its actions constituted infringement of these valid patents.

11 137. AMAT knew or should have known this objectively high likelihood, at least  
12 because AMAT was made aware of the patents-in-suit through Dr. Cohen’s counsel.

13 138. On information and belief, and based on the events described in paragraphs 36–  
14 39, AMAT deliberately copied or drew upon Dr. Cohen’s patented technology in developing the  
15 AMAT Volta System for manufacture of the Accused Chips.  
16

17 139. AMAT’s ongoing direct and induced infringement of the patents-in-suit,  
18 copying and/or use of the patents-in suit subsequent to viewing Dr. Cohen’s in-person  
19 presentations, receiving Dr. Cohen’s multiple communications about the patents-in-suit, and  
20 declining to take a license to the patents-in-suit, constitutes egregious misconduct beyond typical  
21 infringement.  
22

23 140. The infringement of the patents-in-suit alleged above has injured Dr. Cohen and  
24 thus, Dr. Cohen is entitled to recover damages adequate to compensate for AMAT’s infringement,  
25 which in no event can be less than a reasonable royalty.

26 141. Because AMAT willfully infringed the patents-in-suit, Dr. Cohen is permitted  
27 under 35 U.S.C. § 284 to recover treble the amount of actual damages sustained by the Plaintiff.  
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- 1 E. Finding that Huawei Device (Dongguan) Co., Ltd. has infringed one or more claims of the  
2 '668 patent, one or more claims of the '226 patent, one or more claims of the '052 patent,  
3 and one or more claims of the '445 patent;
- 4 F. Finding that HiSilicon Technologies Co., Ltd. has infringed one or more claims of the '668  
5 patent, one or more claims of the '226 patent, one or more claims of the '052 patent, and  
6 one or more claims of the '445 patent;
- 7 G. Finding that Applied Materials, Inc., has infringed one or more claims of the '668 patent,  
8 one or more claims of the '226 patent, one or more claims of the '052 patent, and one or  
9 more claims of the '445 patent;
- 10 H. Awarding Dr. Cohen all allowable damages flowing from the defendants' infringement of  
11 the '668 patent, the '226 patent, the '052 patent, and the '445 patent, which can be no less  
12 than a reasonable royalty under 35 U.S.C. § 284;
- 13 I. Finding that Taiwan Semiconductor Manufacturing Company, Ltd. and TSMC North  
14 America Corp. have willfully infringed the '668 patent, the '226 patent, the '052 patent, and  
15 the '445 patent, and awarding Dr. Cohen all allowable damages for their willful  
16 infringement, including but not limited to an award of three times Dr. Cohen's actual  
17 damages pursuant to 35 U.S.C. § 284;
- 18 J. Finding that Applied Materials, Inc. has willfully infringed the '668 patent, the '226 patent,  
19 the '052 patent, and the '445 patent, and awarding Dr. Cohen all allowable damages for  
20 their willful infringement, including but not limited to an award of three times Dr. Cohen's  
21 actual damages pursuant to 35 U.S.C. § 284.
- 22 K. Awarding Dr. Cohen his costs, and pre-judgment and post-judgment interest on his damages  
23 caused by the defendants' infringement of the '668 patent, the '226 patent, the '052 patent,  
24 and the '445 patent, and/or otherwise, as the Court may deem just;
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1 L. Declaring this case exceptional, in Dr. Cohen’s favor, and awarding Dr. Cohen his  
2 attorneys’ fees in this action pursuant to 35 U.S.C. § 285 and/or other applicable authority;  
3 and

4 M. Granting Dr. Cohen such other and further legal and/or equitable relief that is just and proper  
5 under the circumstances.  
6

7 **DR. COHEN’S ANSWER TO AMAT’S DECLARATORY JUDGMENT COMPLAINT**

8 Dr. Cohen respectfully answers the numbered paragraphs of Declaratory Judgement  
9 Plaintiff Applied Materials, Inc.’s, Complaint for Declaratory Relief (Case No. 5:17-cv-04990, Dkt.  
10 1) (the “AMAT DJ Complaint”) as follows below. All allegations not expressly admitted are  
11 denied. Dr. Cohen further incorporates the preceding Consolidated Amended Complaint in  
12 response to and as counterclaims to the AMAT DJ Complaint.  
13

14 1. Dr. Cohen admits that AMAT has asserted a declaratory judgment action concerning  
15 the patents-in-suit. Dr. Cohen denies the remainder of the allegations of ¶1.

16 2. Admitted.

17 3. Denied.

18 4. Dr. Cohen lacks sufficient knowledge or information to admit or deny the  
19 allegations of ¶4, and, on that basis, Dr. Cohen denies them.  
20

21 5. Admitted.

22 **THE PARTIES**

23 6. Admitted.

24 7. Admitted.

25 **BACKGROUND AND THE CONTROVERSY**

26 8. Dr. Cohen admits that on May 5, 2017, Dr. Cohen sued Taiwan Semiconductor  
27 Manufacturing Company Limited and TSMC North America, along with Apple, Inc. and various  
28

1 Huawei entities, in the U.S. District Court for the Eastern District of Texas for infringement of four  
2 patents vis-à-vis chips manufactured by TSMC.

3 9. Admitted.

4 10. Dr. Cohen admits that the “EDTX Customer Suit complaint” recited the language  
5 as noted in ¶10. Dr. Cohen denies the remainder of the allegations of ¶10.

6 11. Admitted.

7 12. Admitted.

8 13. Dr. Cohen lacks sufficient knowledge or information to admit or deny the  
9 allegations of ¶13, and, on that basis, Dr. Cohen denies them.

10 14. Dr. Cohen admits that he has alleged that TSMC directly infringes the patents-in-  
11 suit. Dr. Cohen lacks sufficient knowledge or information to admit or deny the allegations of ¶14,  
12 and, on that basis, Dr. Cohen denies them.

13 15. Dr. Cohen lacks sufficient knowledge or information to admit or deny the  
14 allegations of ¶15, and, on that basis, Dr. Cohen denies them.

15 **JURISDICTION AND VENUE**

16 16. Admitted.

17 17. Admitted.

18 18. Dr. Cohen admits that he is a resident of California. Dr. Cohen consents, solely and  
19 exclusively for the purposes of the above captioned case, to the Court’s exercise of personal  
20 jurisdiction over him. To the extent a further answer is required, Dr. Cohen denies the balance of  
21 the allegations of ¶18.

22 19. Dr. Cohen admits that he resides in the Northern District of California, and, solely  
23 and exclusively for the purposes of the above captioned case, consents to venue in this District.

24 **COUNT 1: Declaratory Judgment of Non-Infringement of U.S. Patent No. 6,518,668**





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**CERTIFICATE OF SERVICE**

I hereby certify that on March 1, 2018, I electronically filed the foregoing PLAINTIFF DR. URI COHEN’S THIRD CONSOLIDATED AMENDED COMPLAINT AND ANSWER TO COMPLAINT FOR DECLARATORY JUDGMENT with the Clerk of the Court using the ECF system which will send notification of such filing to all attorneys of record registered for electronic filing.

/s/ Suneel Jain  
Suneel Jain